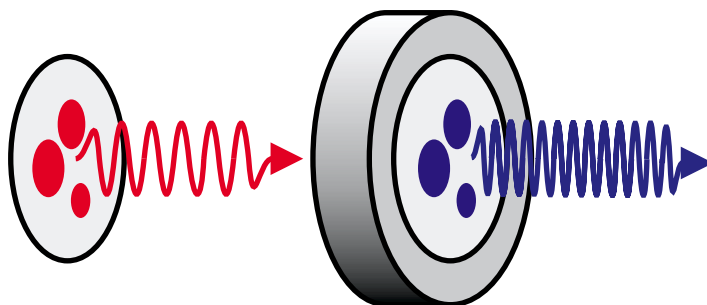


Ultra Fast Semiconductor-Gas Discharge Infrared Imagers



1.1 – 3.6 μm (Si:Zn)
1.1 – 10.6 μm (Si:In)
0.9 – 1.7 μm (GaAs:Cr)

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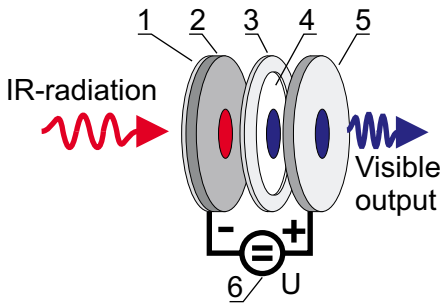
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I. Principle of Operation & Cell Design

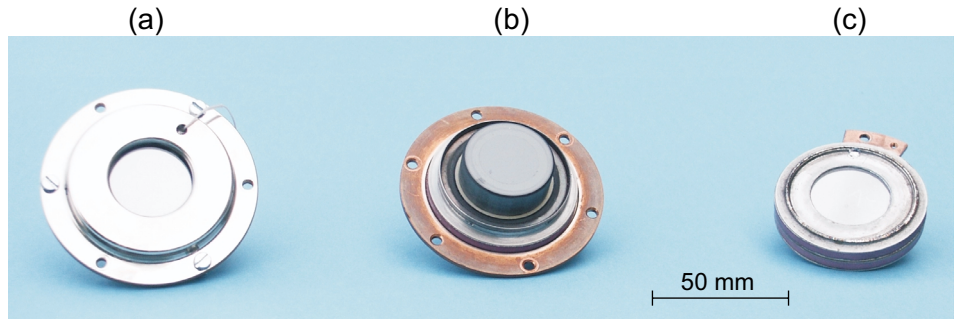


IR converter cell modules of different designs:

- (a) shielded cell with a conventional output
- (b) cell with a fiber optical output
- (c) special lightweight cell for operation with a Stirling micro cooler

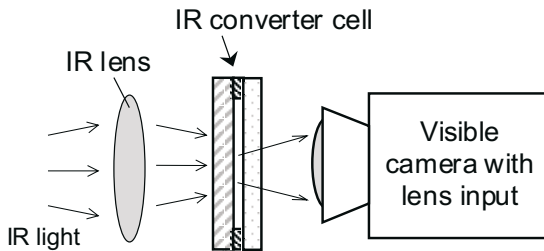
Schematic of the semiconductor-gas discharge infrared-to-visible converter:

- 1 transparent cathode
- 2 photosensitive semiconductor
- 3 dielectric spacer
- 4 gas discharge gap
- 5 transparent anode
- 6 high voltage power supply

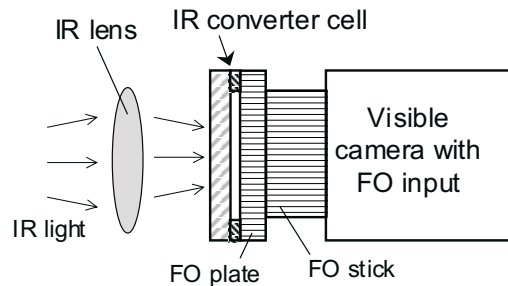


II. Integration with acquisition cameras...

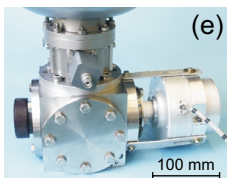
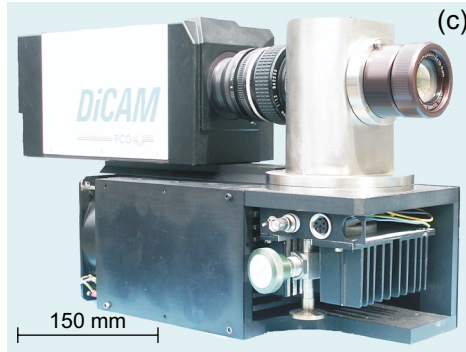
..by relay lens coupling



..by fiber optical (FO) coupling



III. Systems Implementation



(a), (b) Liquid nitrogen (LN₂) cryostats.

(c) IR imaging system utilizing a cooled converter cell chilled by a Stirling cooler (down to 77 K) and coupled with an ICCD camera by means of a relay lens.

(d) Near-IR camera based on an uncooled GaAs:Cr converter cell (black part) FO coupled to an ICCD-camera (silver part).

(e) IR imaging system on the basis of a LN₂-cooled converter cell FO coupled to an ICCD-camera.

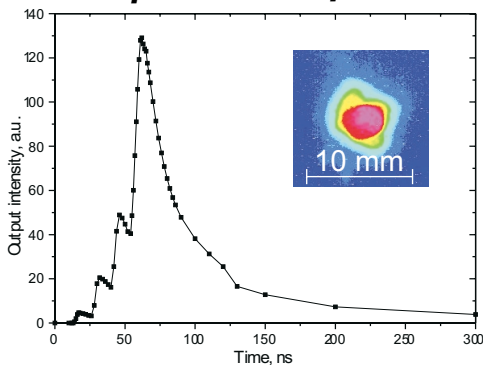
IV. Main Technical Parameters

Detector material		Si:Zn	Si:In	GaAs:Cr
Spectral range	μm	1.1 - 3.6	1.1 - 10.6	0.9 - 1.7
Wave length of max. sensitivity (λ_{max})	μm	2.3	7.1	0.9
Operation temperature	K	90	90	300
Response time	μs	1 - 10	0.05 - 0.1	0.5 - 5
Max. exposure time	ms	infinity	10	infinity
Active area	mm	27	27	20
Spatial resolution	lp/mm	7 - 13	5 - 8	7 - 13
Effective inscribed format	pix^2	500 x 500	300 x 300	360 x 360
Power conversion efficiency ($W/W * 100 \%$)	%	5 - 15 (at λ_{max})	0.01 - 0.03 (at λ_{max})	0.6 - 2 % (at 1.4 μm)
Dynamic range	-	$>10^5$	>300	$>10^4$
Detectivity,	$\text{cm Hz}^{1/2}\text{W}^{-1}$	$(0.5 - 2) * 10^{11}$ (at λ_{max})	n.a.	n.a.

n.a. - not available

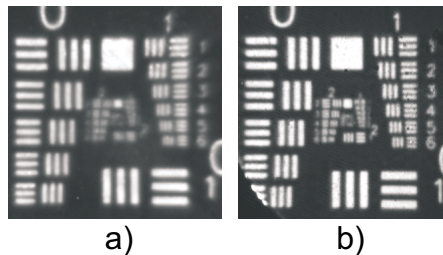
V. Selected Test Results on...

..Speed of response



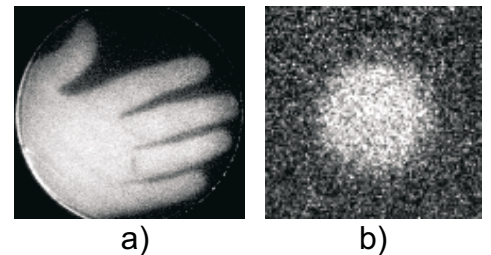
Time response of a Si:In IR converter on a 100 ps laser pulse with a wavelength of $\lambda = 6.9 \mu\text{m}$.

..Spatial resolution



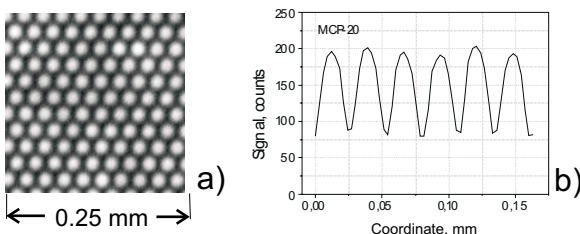
USAF test mask images taken by a Si:Zn IR converter.
 (a) Conventional cell with a homogeneous gas layer. Resolution ~ 8 lp/mm.
 (b) Improved cell with a microstructured gas layer. Resolution ~ 13 lp/mm.

..Sensitivity



Sample thermal images taken by Si:Zn IR imagers with different acquisition cameras (AC).
 (a) Hand image (32-34 C). AC is a low-noise CCD with a F/1.4 lens. Exp. time 1 s, S/N = 20.
 (b) 100 C black body image. AC is a FO coupled ICCD camera. Exposure time 1 μs , S/N = 3.

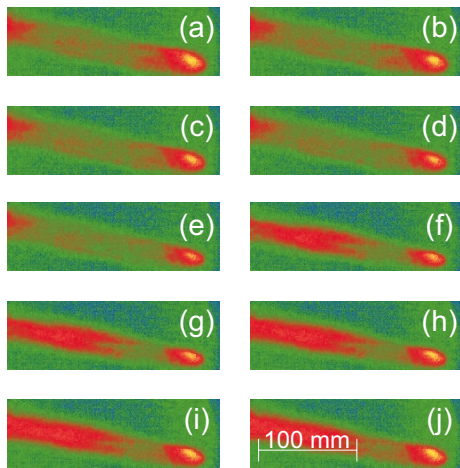
..Microstructuring the gas discharge layer



Exemplary image (a) and glow brightness profile (b) of the gas discharge in the IR converter with a micro capillary plate (MCP). The diameter and the center-to-center distance of capillaries are 20 μm and 27 μm respectively. The modulation depth observed is $\sim 40 \%$. The MCP-limited resolution is 18.5 lp/mm.

VI. Applications: High-Speed Thermography

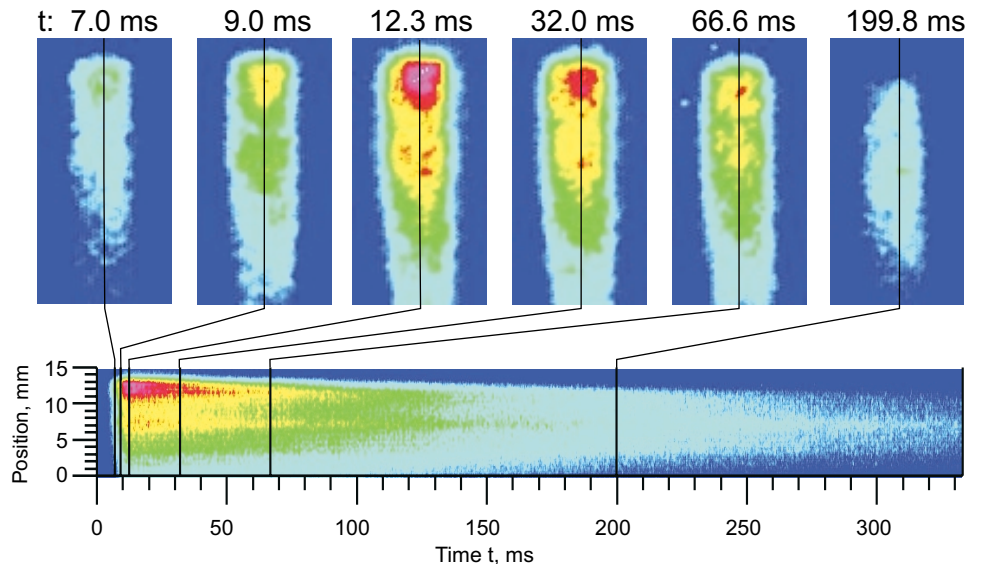
Laser beam welding



Series of thermal images of a laser beam welding process of stainless steel workpieces. The IR imaging system consists of a Si:Zn IR converter and a high speed CMOS camera running at a frame rate of 420 fps.

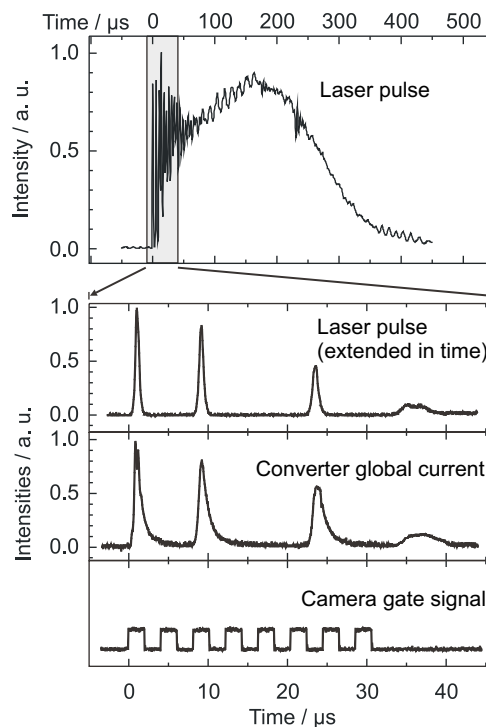
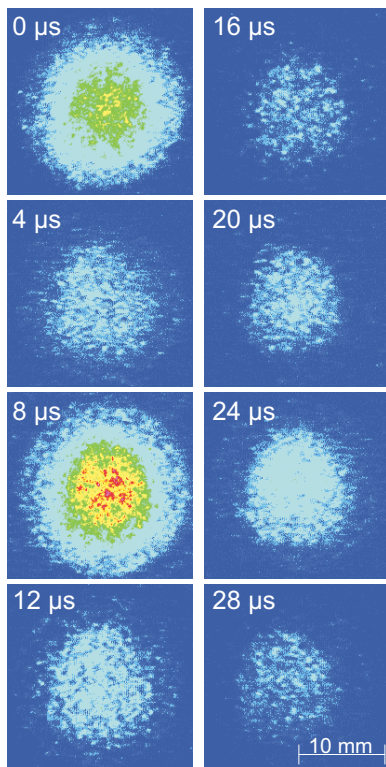
Heating and cooling down of a metallic foil

Selected frame thermal images (above row) and streak thermal image (below) of a metallic foil being heated by a current pulse and then cooled down freely. The IR imaging system consists of a Si:Zn IR converter and a high speed intensified CCD camera which has been run at a frame rate of 3000 fps and an exposure time of 1 μ s.



VII. Applications: Time-Resolved Laser Beam Profiling...

..at a frame rate of 250 000 fps



The laser is a 1.314 μ m Nd:YAG. The IR imaging system comprises a Si:In IR converter and a framing streak camera (Hamamatsu C4187) operating at a frame rate of 250 000 fps and an exposure time of 2 μ s. Time values in the pictures are delay times of the gating pulse.

..of a 2.94 μ m laser (Er:YAG)

The IR imaging system consists of a Si:Zn IR converter and a gated intensified CCD camera. The exposure time is 10 μ s. Time values in the pictures are delay times of the gating pulse. The laser pulse length is 250 μ s.

